

MAY 05 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor : Manfred ROTHLEY et al.
 Serial No. : 09/720,938
 Filing Date : May 2, 2001
 For : APPARATUS FOR SENSING ELECTROMAGNETIC RADIATION
 Group Art Unit : 2878
 Examiner : C. Hannaher

05/05/2003 FFANAEIA 00000091 110600 09720938
 01 FC:1252 410.00 CH

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:
 Commissioner for Patents, Washington, D.C. 20231 on

30 April 2003

Michelle M. Carniaux (Reg. No. 36,098)

Commissioner for Patents
 Washington, D.C. 20231

TRANSMITTAL

SIR:

Please find an Amendment transmitted herewith for filing in the above-identified patent application.

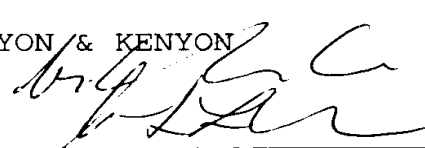
Applicants hereby request a two-month extension of time for responding to the Office Action of December 24, 2002. The extended period for response expires on May 24, 2003. Please charge the \$410.00 extension fee and any other fee that may be required to Deposit Account No. 11-0600. A duplicate of this Transmittal is enclosed.

Respectfully submitted,

KENYON & KENYON

(Reg No 36098)

Dated: 30 April 2003

By: 
 Richard L. Mayer
 Reg. No. 22,490

One Broadway
 New York, NY 10004
 (212) 425-7200

MAY 05 2003

[10191/1694]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Manfred ROTHLEY et al.
Serial No. : 09/720,938
Filed : May 2, 2001
For : APPARATUS FOR SENSING ELECTROMAGNETIC RADIATION
Examiner : C. HANNAHER
Art Unit : 2878

Commissioner for Patents
Washington, D.C. 20231

30 Apr 12 2003

CLINTON & KENYON

AMENDMENT

Dear Sir:

This amendment addresses the Office Action mailed December 24, 2002. Please enter the following amendment in the above-captioned application.

In the Claims:

Please cancel claim 20, without prejudice.

Please amend the claims as set forth below.

19. (Amended) An apparatus for sensing electromagnetic radiation, comprising:
- a detector structure to sense electromagnetic radiation, the detector structure formed on a semiconductor substrate;
 - a protective window for the detector structure, and
 - a micromechanical optical imaging system including a lens configured to form an image of a subject to be imaged onto a plane of the detector structure, the lens having a convexity on a side facing away from the detector structure, the lens being arranged relative to the detector structure so that a cavity is between the lens and the detector structure.